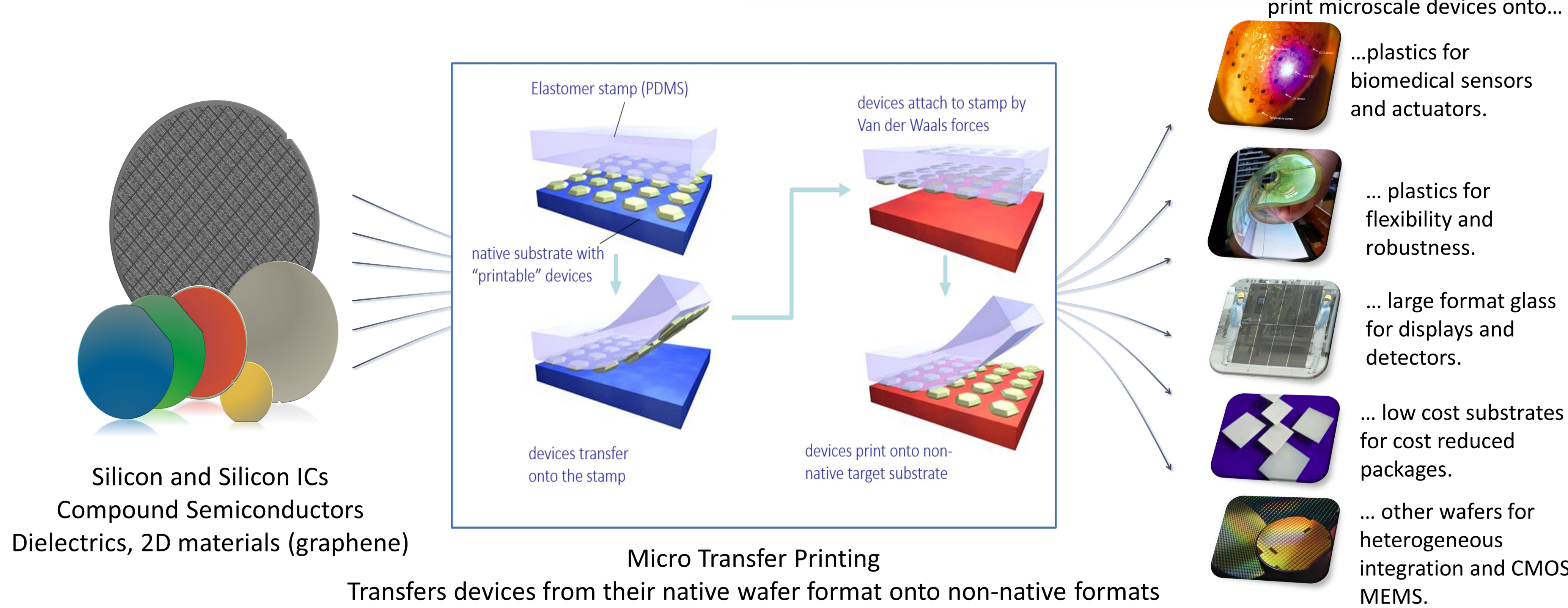


# Manufacturing Capability of Micro-Transfer Printing

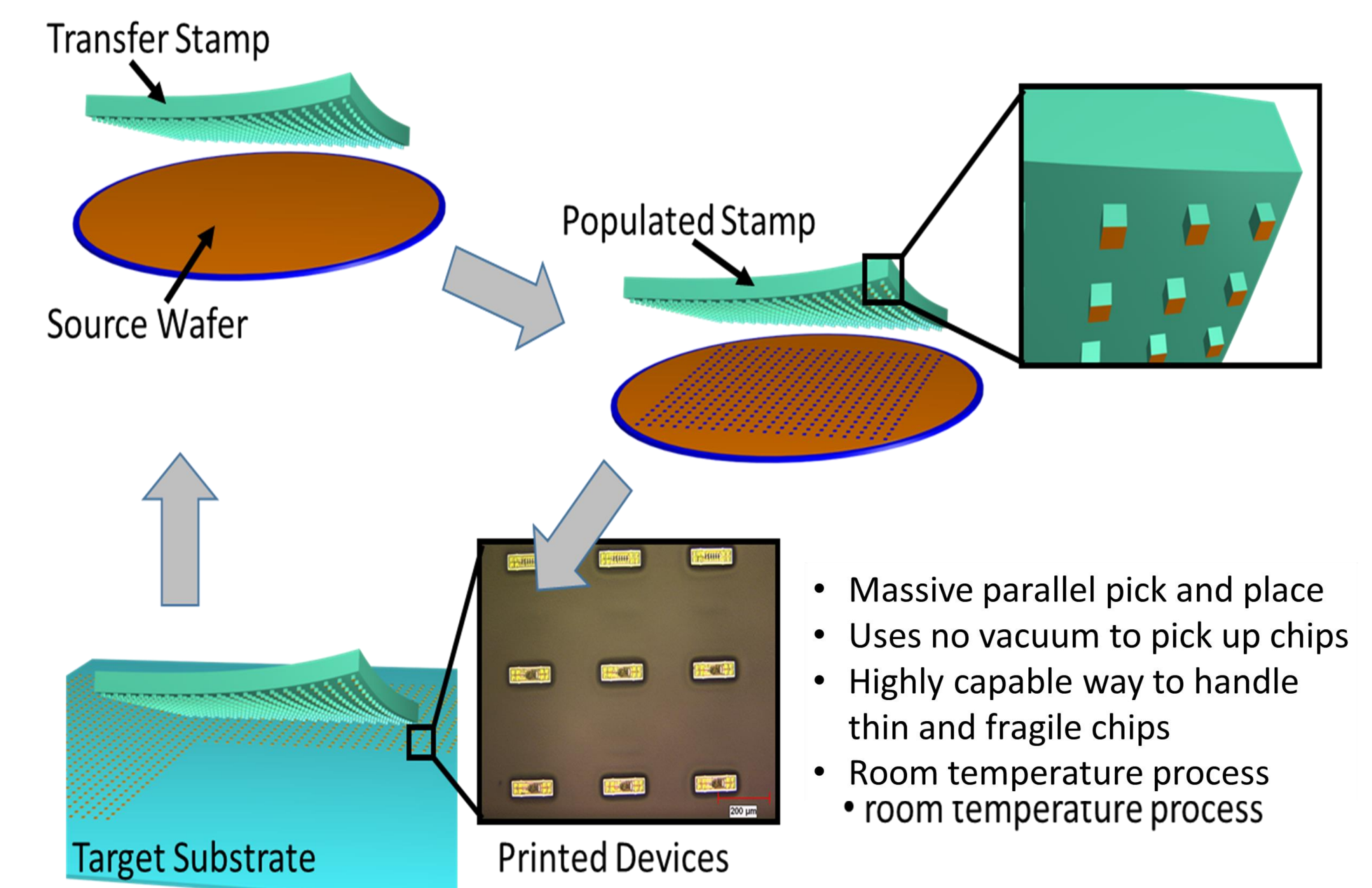
X-Celeprint Inc., Research Triangle Park, NC, [www.x-celeprint.com](http://www.x-celeprint.com), [dgomez@x-celeprint.com](mailto:dgomez@x-celeprint.com)

David Gomez, Tanya Moore, Matthew A. Meitl, Salvatore Bonafede, Andrew Pearson, Brook Raymond, Tiffany Weeks, Kevin Oswald, Erich Radauscher, David Kneeburg, Julia Roe, Alin Fecioru, Steven Kelleher, Raja Fazan Gul, Alexandre Ferrell, Antonio Jose Trindade and Christopher A. Bower

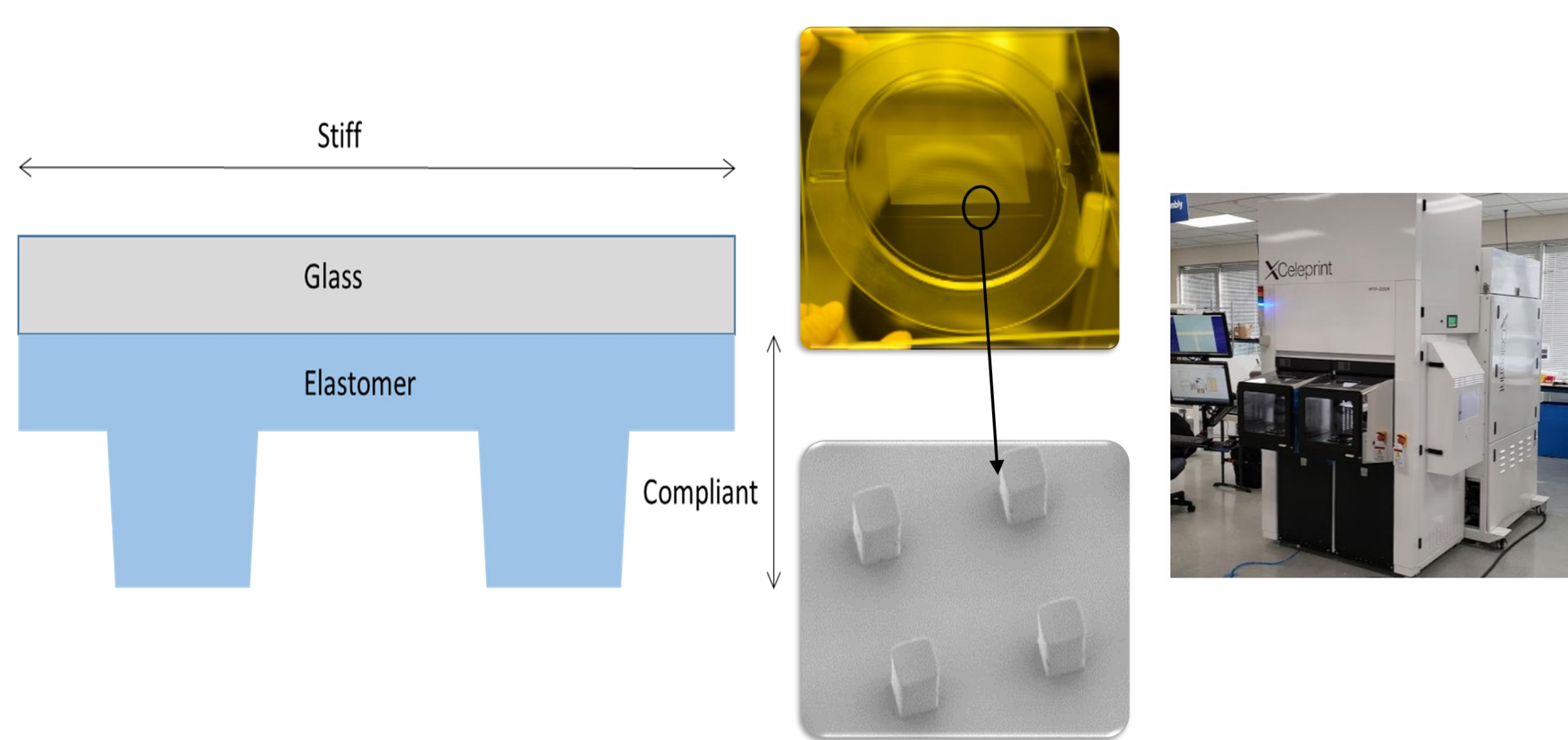
## Micro Assembly Unlocks New Opportunities for Wafer Fabricated Devices



## How it works



## Microscale manipulation with macroscale scalability

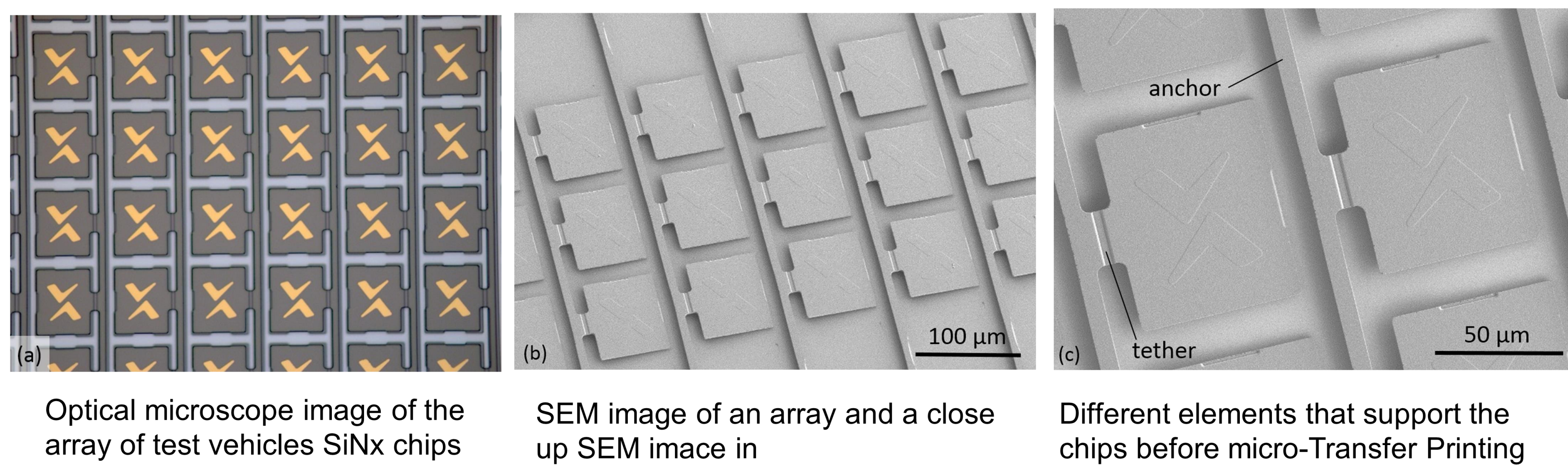
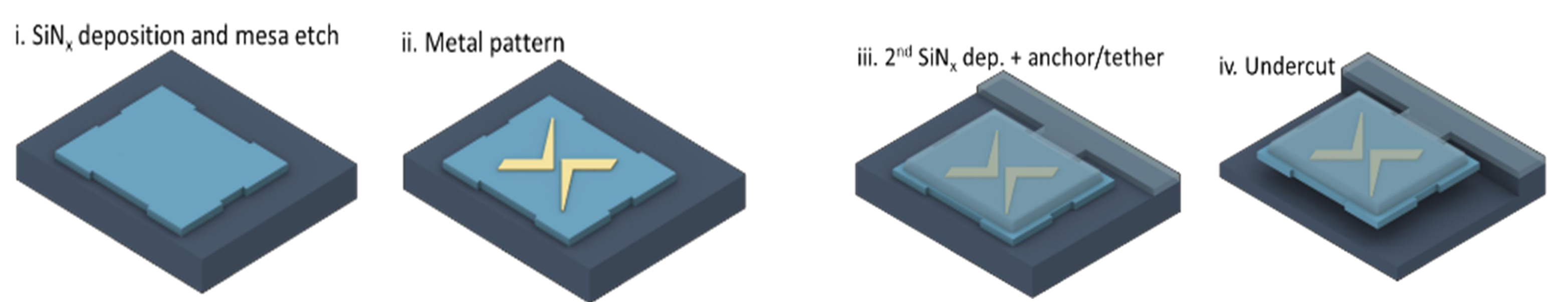


- Naturally compliant in the Z Direction: contacts real-world surfaces over large areas
- Laterally stiff: maintains lateral registration
- Soft contact: Ideal for handling fragile & thin semiconductor devices
- Transparent: Facilitates optical alignment through the stamp during printing
- Low cost: Injection molded with inexpensive materials (glass & silicone)
- Robust: Demonstrated 10's of thousands of print cycles without degradation

## Test Vehicles

- SiNx test chips were generated out of on a silicon surface
- Chips were then released and used for transfer testing.

## Process Flow



## Populating a 150mm wafer in 1 print cycle

- More than 82,000 chips transferred in 1 cycle
- Demonstrated transfer yield of 99.94%

